

Evaluation of a MEMS Solution for Kelvin Probing on Bumps 180µm and Smaller



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Overview

- Background & Motivation
- Issues with Kelvin Probing on Bumps
- Pin and Probe Head Design
- Evaluation Plan
- Results
- Summary & Next Steps

Background and Motivation

• Wafer Level Chip Scale Packages (WLCSP) are used when space is at a premium, as in mobile and wearable electronic products







- Wafer-level test (a.k.a. sorting or multiprobe) is usually the last electrical testing done on WLCSP devices
- The test plans for power management devices include RdsON and related measurements, and these tests require Kelvin contacts for accuracy
 - Kelvin contact two pins, Force and Sense, contact the DUT in the same location, but the two pins should not contact each other
- As WLCSP bumps continue to shrink, landing two pins on the same bump becomes a big challenge

Kelvin Probing on Bumps

• Commonly implemented with wedge tip pogo pins



 But, as the bump diameter decreases below 200µm, the pin landing area curves more sharply, and it becomes more difficult for the pins to land consistently



What Can Go Wrong

• Probe spreading, shifting and rotation



\rightarrow Something different is needed for sub-200µm bumps !

MEMS Spring Pin

• Simple structure with spring and snap-fixed two plungers

LILLE

MEMS Spring

• Low resistance and high current capacity

Assembly

Snap-fit Fix

Photo-Lithography Mfg Method

Inner Plating Low Resistance

Electroformed Pipe

H3C Plunger + Au-Plating

PCB Side Plunger

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DUT Side Plunger

Various Tip Shape

(Crown, Needle, Flat ···)

Probe Head Schematic – single site



Probe head was built with 16 sites, spaced layout

Balanced Contact Force (BCF) by Site

Data collected after 5,000 touchdowns



Probe Head



No screw heads on wafer side of probe card

Test Plan

'Snapshot' Area: Jump to this area of the wafer for a single touchdown every 1,000 TDs - intervals increased to 10k as the This created a periodic 'sr owns accumulated on the probe head 0 TD 2000 5000 TD TD 50k 50k 1000 10k TD 20k TD TD Small Bump Test Chip < 1mm² die 'Sandbo he wafer 2 x 2 bump array ~ 180,000 die per wfr
 10x
 10x
 10x
 10x

 TD
 TD
 TD
 TD
 TD
10x TD

Probe Marks vs. Touchdowns







1000 TDs

2000 TDs

5000 TDs









50k TDs

10k TDs

20k TDs 30k TDs SWTest | June 2-5,2019

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Kelvin Pin Gap vs. Touchdowns



Average gap size increased about $15 \mu m$ from 0 to 10k TDs, then levelled off

Estimated Pin Lifetime



With the measured wear rate through 50k touchdowns and an end-of-life tip length of $150\mu m$, projected pin lifetime is *a minimum* of 500k touchdowns

Summary & Next Steps

- The P200 MEMS pin and probe head shows consistent probe marks out to 50,000 touchdowns on < 200µm diameter bumps
 - No probe marks observed within 10 μ m of the bump edge
- Average Kelvin gap size increased by ~15µm from 0 to 10k TDs, but then stayed level from 10k to 50k TDs
- Based on pin wear to 50k TDs, estimated pin lifetime is at least 500k touchdowns
 - CRES data (when available) may provide an opportunity to reduce cleaning frequency and extend pin life
- Continue to monitor probe marks and Kelvin gap size out to (at least) 200k touchdowns
- Add contact resistance (CRES) monitoring to the evaluation
 - Will CRES be an indicator of probe position on the bump?
 - *e.g.* higher CRES = probe has slid to bump edge

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Backup Slides

Probe Head with Preload



Recommended Overtravel – 180µm





Probe Marks vs. Touchdowns



1000 TDs



10k TDs



2000 TDs







5000 TDs



50k TDs